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A-2-3 A Low Power 8 Bit Parallel A/D Converter with High Accuracy Process

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An increased tendency to use A/D converters for video signal processing strongly demands a high-speed, low power and high accuracy A/D converter. In a parallel A/D conversion, each comparator must make its decision at the same point in time relative to input waveform. The comparator relies on component matching to minimize comparator-to-comparator-timing skew (a factor of the apperture uncertainty) and offset voltage mismatch. The offset voltage mismatch of pair transistors, $\Delta V_{\rm BE}$ is expressed as:

 $\Delta V_{BE} = \frac{kT}{q} \lambda_n \frac{\beta_{SE2} \cdot h_{FE2} \cdot S_2}{\beta_{SE1} \cdot h_{FE1} \cdot S_1} + (R_{C1} - R_{C2}) I_E$

where ρ_{SE} , S and R_C are sheet resistivity, diffusion area and contact resistance between metal and silicon in the emitter region, respectively. Suffixes 1 and 2 indicate either of pair transistors. In our experiment, $R_{C1} - R_{C2}$ was controlled to be less than 2Ω even in 3 μm square contact area. Further distributions of emitter sheet resistance and emitter area were suppressed down to 1 - 2% by adopting ion implantation technique for emitter and 10 to 1 reduction optics wafer stepper. As a result, ΔV_{BE} value is affected mainly by h_{FE} difference. Figure 1 shows the relation of the $\Delta V_{\rm BE}$ values between measured and calculated from measured h_{FF} difference. To improve h_{FF} difference of pair transistors, serial implantation of B^+ and As^+ was tried through the same window. Generally the ion implant causes residual defects in the base region even if it is followed by thermal annealing¹⁾. The leakage current of emitter-base junction across these defects region causes a variation of $h_{\rm FE}$. Defect region remained only in the emitter surface region by serial implantation of B^+ and As^+ through the same window. Therefore transistor having small $h_{\rm FE}$ value due to large leakage current appeared only a little. Figure 2 shows the distribution of the hFE for various emitter and base processes. To improve the accuracy of DC reference voltage determined by a single metal line, the mask of photolithography is produced by using electron beam. Figure 3 represents linearity error, or fraction of DC reference voltage versus output code number. As shown in Fig. 3, fractions of DC reference voltage for each comparator are less than 1/4 LSB. Low pressure epitaxial method with slight auto doping is used to reduce bipolar device size. Standard size of collector and contact are $35 \times 22 \ \mu\text{m}^2$ and $3 \times 3 \ \mu\text{m}^2$, respectively. The value of $f_{
m T}$ of this transistor is 2 GHz. In designing parallel A/D converter, optimized comparator stage was developed which was reduced both in the number of transistors and in power consumption. High speed operation was made possible by using high gain current-driven latch based on positive feedback. For the reduction of the transistors counts (17 transistors per stage), wired-or logic was introduced into the comparator. Table 1 summarizes the electrical characteristics of the 8 bit A/D converter. Since the power consumption is 800 mW, conventional package can be used which dispenses with radiation plate or fin. The figure of merit of this device²) is 1.2×10^{10} (Hz/W), or 3 - 4 times better than that achieved by conventional 8 bit parallel converters. Figure 4 shows the reconstruction of a 10 kHz sinewave, sampled at 40 MHz to 8 bit accuracy. This work was supported by the Ministry of International Trade and Industry of Japan.

References

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 $(\triangle V_{BE'} CALCULATED FROM MEASURED h_{FE})$

Fig.l. The relation of the $\rm V_{\rm BE}$ values between measured and calculated from measured $\rm h_{\rm FE}$ difference.













Fig.4. Reconstruction of a 10 kHz sinewave sampled at 40 MHz to 8 bit accuracy.